

06-02

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Agent Docket No.: Stanford MxL 01

#5

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the Application of)
Charles D. SCHAPER)
Application No: 09 / 898,521)
Filed : July 3, 2001)
Title: **Molecular Transfer lithography**)
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Palo Alto, California 94306
June 6, 2002

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR § 1.97

Assistant Commissioner for Patents
U.S. Patent and Trademark Office
Washington, DC 20231

TO THE COMMISSIONER FOR PATENTS:

In accordance with the duty of disclosure under 37 CFR § 1.56 and in accordance with 37 CFR § 1.97 and 37 CFR § 1.98, enclosed is an Information Disclosure Statement PTO-1449B substitute, together with photocopies of the ten articles cited on that form.

It is requested that the cited documents be considered by the Examiner in the examination of the above cited patent application, and that the enclosed copy of the Information Disclosure Statement Form PTO-1449 be initialed by the Examiner to indicate such consideration, and that a copy of this initialed form be returned to the applicants.

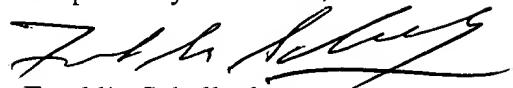
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Please address all further correspondence to

Franklin Schellenberg
4023 Villa Vista
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Respectfully submitted,



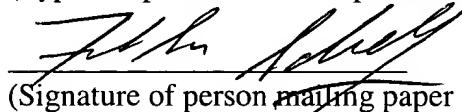
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Substitute for form 1449B/PTO**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet

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of

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Complete if Known

Application Number	09 / 898,521
Filing Date	July 3, 2001
First Named Inventor	Charles D. SCHAPER
Group Art Unit	
Examiner Name	
Attorney Docket Number	STAN MXL 001

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
		Stephen CHOU, Peter KRAUSS, & Preston RENSTROM. "Imprint Lithography with 25-Nanometer Resolution", Science Vol. 272, April 5, 1996 pp. 85-87, USA.	
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		Shinichi UEKI, Isao ASHIDA, & Hiroichi KAWAHIRA, "New data processing of dummy pattern generation adaptive for CMP process", in Photomask and X-Ray mask Technology VI, H. Morimoto, ed. Proceedings of the SPIE Vol. 3748, April 1999 pp. 265-272, USA.	
		M. COLBURN, S. JOHNSON, M. STEWART, S. DAMLE, T. TAILEY, B. CHOI, M. WEDLAKE, T. MICHAELSON, S.V. SREENIVASAN, J. EKERDT, & C. Grant WILLSON, "Step and flash imprint lithography: A new approach to high-resolution printing", in Emerging Lithographic Technologies III, Y. Vladimirs, ed. Proceedings of the SPIE Vol. 3676, March 1999 pp. 279-389, USA.	
		P. RUCHHOEF, M. COLBURN, B. CHOI, H. NOONU, S. JOHNSON, T. BAILEY, S. DAMLE, M. STEWART, J. EKERDT, S.V. SREENIVASAN, J.C. WOLFE, & C. Grant WILLSON, "Patterning curved surfaces: Template generation by ion beam proximity lithography and relief transfer by step and flash imprint lithography", Journal of Vacuum Science & Technology B Vol. 17(6), Nov/Dec. 1996 pp. 2965-2969, USA.	

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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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